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Sheet 1 of 2

Complete if Known

Application Number	10/072,656
Filing Date	February 7, 2002
First Named Inventor	Eric Prophet
Group Art Unit	2811
Examiner Name	Not Yet Assigned
Attorney Docket Number	269/132

U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)			
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Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
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OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
Loke		TAS, N. et al., Side-Wall Spacers for Stiction Reduction in Surface Micromachined Mechanisms	
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Examiner Signature	Loke	Date Considered	8/20/03
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¹ Unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

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